

U.S. DEPARTMENT OF COMMERCE

PATENT AND TRADEMARK OFFICE

LIST OF REFERENCES CITED BY APPLICANT(S)

(Use several sheets if necessary)

Date Submitted to PTO: October 23, 2001

ATTY DOCKET NO.

862.C2173

APPLICATION NO.

09/819,906

APPLICANT

Yasuhiro SHIMADA, et al.

FILING DATE

March 29, 2001

GROUP

2881

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
KN	5,834,783	11/10/1998	Muraki, et al.	250	398	
	5,864,142	01/26/1999	Muraki, et al.	250	491.1	
	5,905,267	05/18/1999	Muraki	250	492.22	
	5,981,954	11/09/1999	Muraki	250	397	
	6,107,636	08/22/2000	Muraki	250	492.2	
	6,104,035	08/15/2000	Muraki	250	492.22	
	6,166,387	12/26/2000	Muraki, et al.	250	492.2	
	5,929,454	07/27/1999	Muraki, et al.	250	491.1	
	5,939,725	08/17/1999	Muraki	250	492.22	
	5,973,332	10/26/1999	Muraki, et al.	250	492.2	
	6,137,113	10/24/2000	Muraki	250	492.22	
KN	4,419,580	12/06/1983	Walker, et al.	250	396 R	

FOREIGN PATENT DOCUMENTS

DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)

EXAMINER

K. LUUYEN

DATE CONSIDERED

03-07-03

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered.

Include copy of this form with next communication to applicant.

Sheet 1 of 2

FORM PTO 1449 (modified)		ATTY DOCKET NO. 862.C2173		APPLICATION NO. 09/819,906		
U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		APPLICANT Yasuhir SHIMADA, et al.				
LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)		FILING DATE March 29, 2001		GROUP 2881		
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FOREIGN PATENT DOCUMENTS						
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)						
len	"Sub-Nanometer Miniature Electron Microscope", A.D. Feinerman, et al., Journal of Vacuum Science and Technology A, Vol. 10, No. 4, July/August 1992, 611-616.					
	"High Aspect Ratio Aligned Multilayer Microstructure Fabrication", K. Y. Lee, et al., Journal of Vacuum Science and Technology B, Vol. 12, No. 6, November/December 1994, pp. 3425-3430.					
	"Arrayed Miniature Electron Beam Columns For High Throughput Sub-100 nm Lithography", T. H. P. Chang, et al., Journal of Vacuum Science and Technology B, Vol. 10, No. 6, November/December 1992, pp. 2743-2748.					
	"Microstructures for Particle Beam Control", G. W. Jones, et al., Journal of Vacuum Science and Technology B, Vol. 6, No. 6, November/December 1988, pp. 2023-2027.					
len	"A Multibeam Scheme for Electron-Beam Lithography", T. Sasaki, Journal of Vacuum Science and Technology, Vol. 19, No. 4, November/December 1981, pp. 963-965.					
EXAMINER	k. MAYVEN		DATE CONSIDERED 03-01-03			